

EP-Summaries

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Summary documents of EP working groups at the TTC meetings Frascati

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and KEK

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TTC Meeting WG#3 (KEK Japan)

R&D Efforts on Electropolishing Parameters 25-29 September 2006 Coveners: J. Mammosser, K. Saito, T. Tajima

Goals for this meeting:

The goals for this meeting were to review recent R&D efforts towards EP quality control, collect perspectives from industrial partners on the current process techniques and process quality assurance, review the progress on eliminating problem areas effecting performance, reviewing the current R&D results towards reducing performance spreads and to brain storm on process and system improvements.

• These goals were ambitious but were achieved by extending the meeting times and it is the convener's recommendation to increase the allotted meeting time in additional meeting on electropolish development to allow for increasing the depth of the discussions.

Electropolish Process Quality Control:

The leading concerns for the electropolish process are currently focused on the understanding of the final cavity surface conditions due to the nature of the electropolish process that leaves sulfur and other contaminants on the niobium surface and the ability to measure and control the quality of the electrolyte used for this process. During this meeting several presentations were given on electrolyte quality control. During this meeting the following methods of analyzing the standard EP electrolyte mixture (HF+ H_2SO_4) were introduced and discussed:

- Titration (Henkel Co.)
- Inductively coupled plasma optical emission spectroscopy (Henkel Co.)
- Ionic- chromatography (Henkel Co.)
- Total organic carbon (Henkel Co.)
- Nuclear magnetic resonance (Henkel Co.)
- Fourier transformation infrared spectroscopy- attenuated total reflection (Henkel Co.)
- Ion selective electrode method (FNAL)
- Capillary Electrophoresis method (Nomura Plating Co./KEK)
- Online Reference cells (DESY/JLAB)

Results from discussions on electrolyte QA:

- 1. There has been much activity in investigating what methods are available for electrolyte analysis with heavy input from industry (Nomura Plating and Henkel Co)
- 2. It is clear that no single method can fully analyze the electrolyte (mixture and content) and all methods are expensive, sensitive to errors and are difficult to interpret results. It is therefore extremely important to determine what aspect of these available methods can lead to better control of the process and improved cavity performance and reproducibility. These efforts are focused on the determination of how much HF and its associated ions, are in the electrolyte mixture at various stages of use and should remain a priority.
- 3. There is clearly not enough expertise and/or experience with these methods to implement any as an online QA method. Focus should be to continue using the industrial partners to develop more understanding of these methods, identify and choose key parameters to measure and use external resources (outside measurement labs) where possible to perform measurements until additional expertise is gained within the labs and in industry to determine if online monitoring is necessary and possible.
- 4. The inline IV reference cell implemented at DESY and JLAB is a less expensive approach to understanding how the electrolyte is changing over time. The DESY reference cell should be implemented at all electropolishing facilities to standardize measurement techniques, speedup understanding of how the process is changing and to be able to directly compare these facilities.
- 5. Analysis experiments were carried out by the Henkel Co with control mixtures using various analysis techniques. Two control mixtures were used both were diluted electrolyte solutions, one by adding DI water under low temperature controlled conditions (cool) and the second using city water with no additional temperature control (warm). The summary of results from these measurement are as follows:
 - a. Slightly less fluorine concentration (F and FSO₃H) was measured with the warm than the cooled sample? One would have expected a stronger difference given the volatility of HF with temperature. ??? This test should be repeated to verify results.
 - b. The warm sample had slightly more iron impurities in the solution and was most likely due to the difference in impurity content difference from the waters used to dilute the electrolyte. The other impurity concentrations seemed more consistent with the two mixtures.
- 6. Nomura Plating company/KEK performed several analysis experiments using capillary electrophoresis method. Here samples were procured to first develop calibration curves and then measurements were made on several electrolyte mixtures containing increasing amounts of Nb in solution as well as measuring HF concentrations of their production baths. The following are their results from these measurements:
 - a. Measurements from control samples differed in results than that of the actual production baths for F concentrations. In control samples

the fluorine ion concentrations stayed constant during electropolishing up to 17 g/L of niobium generated in the process. The actual production baths however showed strong drops in fluorine ion concentrations with increasing levels of niobium concentration. This could be due to evaporation of HF from the baths due to the need for exhaust over the baths or removal of hydrogen gas during the processing.

The result on the control sample indicates that CE method can catches the total F^- ion in the EP electrolyte. As the chemical reaction equation in the EP process is well known, how much F^- was consumed is calculated. Therefore, how much active $F^$ ion still remained in the electrolyte is determined by the CP method. This is an important finding.

- b. The electrophoresis method looks promising and additional studies needed for this method and should be supported and continued.
- 7. Additional methods such as Ion selective electrode analysis have been started but additional efforts are needed to understand the impact of this method.

Electropolishing R&D results

KEK has performed several single cell process studies towards a better understanding of performance spread using several process variations using tightly controlled and repeatable procedures. The following is the results from the discussions on these results:

- 1. In a pilot study with newly fabricated cavities a large spread in performance $(39.1 MV/m \pm 8.2 MV/m)$ resulted from the first process cycle using standard KEK procedures. These procedures use CBP (100µm)as a baseline procedure to generate a uniform starting surface finish followed by a light BCP(10µm) to clean the cavity. Field emission onset was the main reason for the spread in performance.
- 2. An additional chemistry: $EP(20\mu m)+EP(3,fresh acid)$ was performed on these cavities with a final chemistry with fresh acid on a closed cavity as the final processing followed by an additional HF rinse to remove chemical surface contamination. Results from this run showed a much improved performance curve (45.8MV/m ± 1.9MVm).
- 3. Additional CBP and similar chemistry ;EP(80)+EP(3, fresh acid) was performed resulting in a spread larger than the second test and smaller than the first process cycle with a 42.5 \cdot 0 MV/m ± 3.4 MV/m.
- 4. The difference of the spread between the first and the second could be understood by the contamination. The difference of the spread between the second and the third is interpreted that the heavy EP(80μm) could produce a persisting contamination.
- 5.
- 6.
- 7. The fresh acid on a closed cavity could make perfect sense that the surface should be cleaner with fresh acid than the typical process procedures. Additionally field emission is the cause for most of the spread and additional rinsing after chemistry seems to help produce less field emission.

- 8. The effects of the CBP are still unclear but it also makes sense that to get reproducible results starting with surfaces that are more uniform should lead to polishing that is more uniform and surfaces that are more reproducible.
- 9. The conveners recommend using CBP for further studies on nine cell cavities as a means to understand its impact in comparison with performance limits from the standard process and as a means to recover cavity performances from early quenches.

Results from Discussions on System and Process Improvements

During this meeting many times the discussions turned to what in this process should be changed to improve it in both method and hardware. The following is a summary of these discussions:

- 1. Most importantly all systems in current use have significant differences in both process used as well as hardware design. These differences are in some cases subtle and in other cases dramatic but all may have an effect in the end results for the process performance. Much of the discussions are aimed at flushing out these differences and trying to understand them.
- 2. One of the main areas of concern is the small volume of electrolyte used at DESY as well as JLAB. With increasing concern for precipitation of sulfur due to heating, excess niobium concentrations, contamination and loss of HF in the electrolyte, a small volume of electrolyte should make the process more sensitive to any of these problems. The result

of these discussions is that all agreed that a larger volume of electrolyte would be better for consistent results and current system are difficult to change this feature but future designs should take this into consideration.

- 3. Current system designs have all produced good results and should be adequate to understand and improve the current process. Any major changes to the current process could reset the learning curve.
- 4. All agreed that constant current control should be implemented for S0 studies but first demonstrated on single cell test cycles to ensure compatibility then be scaled to nine cell cavities.

Progress since last TTC meeting

During this meeting, a careful review of the list generated for the possible causes for performance spread was performed and resulted in removing the following items that were listed:

Scatter resulting from subtleties of EP process?

- 1. Process parameters: non-reproducibility, non-uniformity of material removal, Set-up: acid level, cathode bag, cathode shielding, current leads, T-control
- 2. Reproducibility in acid composition (DESY), Draining and rinsing: overheating? for multi-cell cavities

Scatter caused by "environmental" problems?

- 3. Malfunction of system,
- 4. Vacuum problems,
- 5. Problems during testing

Reasons for removal of these items:

1. DESY has done such a great job at controlling and documenting each production process cycle that significant evidence exist to be able to remove these possible problems due to the tight control of their procedures and processes. Data from these procedures shows that they were reproducible and indicates that the spread in performance was not due to variations from these items listed but most likely some other variable that is not directly measured or controlled as of yet.

Items left on the list:

- 1. Problems during rinsing and/or assembly
- 2. Human errors
- 3. Q-disease: unpredictable material?

These items were left on the list due to no strong evidence supporting their removal. There are currently two spreads in performance that are forming the large distribution of performances, early field emission onset and early quenches. There is strong evidence that early field emission is mainly due to generic surface contamination and can be easily modified by additional cleaning steps.

After the electropolish process step the cavity surface is in its most contaminated state and there is concern that additional cleaning steps are not currently adequate to produce consistent results. The major concern is sulfur contamination which is non soluble and extremely difficult to remove and that the HPR cleaning may not be reproducible between labs or effective in covering all surfaces of the cavity interior.

Both of these topics are subjects of TTC studies currently and need to be addressed for S0/S1 efforts to be successful. Human errors are still problematic but results can be successfully identified and separated from study results. Qdisease is less of a problem today with very few cases during DESY production cycles and with none identified this year?

This is still not understood It has already been determined that the S0 testing shall include Q-disease tests until evidence supports removing this additional step from the testing process.

Additional topics discussed:

- Field emission must be solved at each lab due to the differences in facilities, system hardware and procedures in use, there can be no single cure for all facilities. What is important is to discuss and share results from investigations performed and to develop a better understanding of the differences of each system and procedures used. What would help this process would be to start implementing the same measurements at each location where possible, record the same parameters and openly share data from processes and cavity test results, there is already good progress in this area.
- Large grain single cell cavity tests have shown excellent results even without EP and more studies should be carried out to determine the spread in performance from this material in comparison with small grain structures.

Recommendations to TTC Board

1. DESY needs to document evidence to remove said items from the Frascati list (Reschke)

- 2. TTC board needs to manage efforts on reducing field emission (Coordination of resources and direction)
- 3. DESY must provide EP I/V cell design to be implemented at other labs, this is the easiest way to compare system performance (Matheisen)
- 4. Labs working on tight loop must identify an electrolyte QA program and provide details and an implementation schedule by end of this year KEK (Saito), Jlab (Mammosser), DESY (Matheisen)
- 5. Need to complete EP operational specifications by end of this year, (Tajima)
- 6. At next TTC meeting:
 - 1. DESY will provide analysis of the next 30 RF tests (Matheisen)
 - 2. JLAb will provide analysis of all tight loop RF tests (Mammosser)
 - 3. KEK will provide analysis of all tight loop RF tests (Furuta)
 - 4. JLab will implement and provide field emission data from witness samples from tight loop (Mammosser)
- 7. TTC board in collaboration with ILC S0/S1 group must determine what and how data is going to be managed for this R&D effort
- 8. Saito (KEK) will coordinate efforts towards resolving correct method for removal of sulfur and be implemented by end of March 07
- 9. TTC board should review or assign task to review field emission reduction plans at each lab
- 10. Labs must provide their detailed plans for reduction in their performance spread by the end of this year

<u>Proposal for an R&D Plan towards better Understanding of</u> <u>the Electropolishing of Niobium Cavities</u>

P. Kneisel, K. Saito, D. Reschke Jan. 17, 2006

During the last year issues concerning the electropolishing of niobium cavities have been discussed at various meetings such as the TTC meeting at DESY in March 2005, the ILC Snowmass workshop, the SMTF workshop at FNAL in October 2005 and now at the TTC meeting in Frascati.

A summary report about Electropolishing activities worldwide will be published in the near future [1]

It has become very clear that the major problems have to do with contamination of the electropolished surfaces as well as with unpredictable hydrogen dissolution, resulting in some cases in "Q-disease". Better "on line" monitoring of the process seems to be a desirable QA/QC activity.

A. Contamination and Rinsing studies

Already in 1971, when the electropolishing process was developed at Siemens AG in Germany [2], it was recognized that the electropolished surfaces were contaminated with residue from the polishing bath mixture of hydrofluoric acid (10 parts) and concentrated Sulfuric acid (85 parts) and that rinsing of the surfaces was a very important step in the surface preparation. At Siemens rinsing in a diluted solution of hydrogen peroxide was as well applied as a subsequent step/several steps of anodizing in ammonium-hydroxide solution and stripping the pentoxide in hydrofluoric acid under ultrasonic agitation (oxipolishing) The rinsing in peroxide solution had the effect of fully oxidizing reaction compounds on the surface to soluble chemical products. Electropolished surfaces were investigated with XPS by Grunder [3] at the Kernforschunszentrum Karlsruhe and he found – besides various states of oxidation – sulfur in the form of sulfate and fluorine F^- . The sulfur contamination, which seems to be obvious by the odor of the surfaces (even after evacuation and exposure and after high temperature heat treatment), could be totally eliminated by by oxipolishing, whereas boiling the samples in water reduced the sulfur contamination by a factor of 10 and converted the sulfate state to a sulfide state. The fluorine contamination could not totally be removed by either treatment, but was significantly reduced.

During the TRISTAN R&D and production phase K.Saito [4] developed – process – "continuous starting from the Siemens horizontal" electropolishing, which is the presently used technique for multi-cell elliptical cavities in most laboratories (exceptions are Cornell University, where vertical electropolishing is developed and at Argonne National Lab, where the Siemens intermittent electropolishing is applied). During the mass production, sulfur contamination of the bath was encountered at a rate of 4 mg/l of solution for a 80 micron material removal on a 5-cell TRISTAN cavity. It was promoted by the buffing abrasive contamination in the EP acid, which was applied to remove mechanically surface defects prior to the heavy EP (80 micron). Investigations showed, that the precipitation of sulfur in the bath could be reduced by rinsing the system with CCL_4 , CS_2 or acetone or by filtration with activated carbon. Consequently, KEK added a pre-EP (3micron) process before the heavy EP (80micron) in order to remove the contaminated surface layer from the buffing. The acid used for pre-EP was only used for this purpose. The TRISTAN cavities were treated in a batch of four cavities. EP acid was replaced every four cavities EP (80micron). The TRISTAN cavities apparently did not suffer from sulfur surface preparation, because KEK used new EP acid for the final EP (10micron) after the EP acid contamination problem and rinsed in peroxide solution. However, they observed a soft MP(2-point 1st order) barrier around Eacc~7MV/m in every cavity, which might still indicate a contamination problem.

Sulfur contamination in the electropolishing system at DESY has been reported since quite some time [5] and it is suspected that sulfur deposits on the surface are in some cases responsible for early onset of field emission at fields ≤ 25 MV/m. This suspicion is based on a comparison of repaired cavities from cryomodule 3, which were prepared by BCP in the same time period as the EP cavities and did not show field emission, excluding problems with the HPR system or during assembly. Sulfur can be dissolved in alcohol as initial tests have shown.

In the context of the CARE/JRA1 in work package 5.1, carried out at Saclay, optimization studies on electropolishing solutions and parameters are undertaken. In these studies it has also been found that sulfur is a contaminant on the polished surfaces and in the polishing system [6]. The generation of sulfur is inherent to the polishing mixture and the process.

- <u>Studies of surface contamination of EP surfaces with appropriate</u> <u>surface analytical methods are highly desirable and by applying</u> <u>different rinsing procedures one should be able to re-confirm the</u> <u>results from 3 decades ago</u>.
- <u>In parallel, rinsing studies on single cell cavities should be carried</u> <u>out to optimize cavity performance.</u>

As a reasonable procedure one can employ a reference cavity with a baseline performance, which will be in subsequent steps always electropolished by a chosen amount, eg. 10 micron, and rinsed differently. By carrying out at least 3 experiments per rinsing procedure, one should get some limited statitistics.

An alternative procedure could be to use several different cavities for each rinsing activity. However, one has to bring each of these cavities to high performance, possibly multiplying the amount of effort going into this activity.

<u>B. "Q – disease"</u>

In 1991 it was discovered [7] that cavities made from high purity niobium can suffer from unexpected losses of several orders of magnitude, if they are exposed to temperatures between 150K and 75 K for longer periods of time. This increase in losses was in subsequent investigations at several laboratories identified as caused by precipitation of hydrogen in the form of the α -hydride; it happens, when interstitially dissolved hydrogen in the niobium matrix can cluster into this hydride. The interstitially dissolved hydrogen enters into the metal during the chemical surface treatment of the niobium either by BCP or electropolishing. (Is this true? During chemical processing, doesn't generated hydrogen as a byproduct of the chemical reaction enter into the bulk Nb??) Remedies against the uptake of hydrogen/Q-disease are a surface treatment at low temperature (<15 C of the acid bath) in the case of BCP, shielding of the cathode with a cathode bag and possibly adding a small amount of nitric acid [8] to the acid mixture in the case of electropolishing. In general, hydrogen can be degassed in UHV at temperatures \geq 600C (hydrogen degassing procedures applied to RRR niobium range from 600C for ~ 10 hrs to 800 C for 3 hrs), preventing Q-disease; also, a rapid cooldown of the cavity through the dangerous

temperature region prevents the precipitation of residual hydrogen into hydrides. However, this procedure might not be applicable for large cryosystems such as an ILC cryomodule. Therefore it is important to eliminate the possibility of additional losses caused by this phenomenon; a degassing heat treatment as has been applied e.g. to the cavities during the TRISTAN construction, would contribute to additional costs in the cavity preparation.

It has been reported [9] that in some cases Q-degradations were encountered unpredictably on 9-cell TESLA type cavities, even though the electropolishing procedures had been applied identical to cavities, which did not suffer from degradation.

At KEK, where presently a very successful single cell program is being pursued with a modified surface treatment procedure consisting of centrifugal barrel polishing, heat treatment and electropolishing, no Qdisease has been identified. However, prior to this outstanding results, cavity performances were very mixed and only after the appropriate electropolishing conditions were re-established at the electropolishing shop have these excellent results been obtained [10]

It seems to be very important to understand the conditions, under which Qdisease is encountered. For this to happen, the following R&D activities are proposed:

- Each test of an electropolished cavity should be tested for Q-disease, meaning, that after an initial test, which might not show a Qdegradation because of fast cooldown, the cavity should be held for ~ 12 hrs at a temperature around 120C and then re-cooled again. Such a test sequence will give a baseline for the frequency of Qdegradations due to precipitation of hydrogen.
- Another possible source of non-reproducibility could be encountered during the rinsing procedure of the cavities at the end of an electropolishing cycle. The cavity surface is covered with an acid film (and possibly there is quite a bit of acid trapped in piping and fixturing volumes, which cannot be drained very well), which will react exothermically with the rinsing water and possibly raise the surface temperature. It is known from experiments with bcp [11] that a surface temperature above ~ 30 C increases the amount of hydrogen pick-up by the niobium. Single cell cavities, which usually do not show Q-disease (after fast cooldown) are easier to handle and might be less vulnerable to this potential source of hydrogen pick-up.

In addition, the niobium, when covered with a thin acid film containing hydrofluoric acid, has no protective oxide layer, which can prevent the pick-up of hydrogen. This situation is the same at the beginning of an EP cycle, where EP acid is put into the cavity without any voltage potential, which can prevent the hydrogen-ion from entering into the niobium material.

It is recommended that a series of tests be made, which explore these possible sources of hydrogen dissolution in the niobium.

• The electropolishing process as applied presently is done at an acid temperature of > 30C, a temperature, which for the bcp process is significantly too high. The hydrogen emanating from the process is being shielded from the non-exposed part of the cavity (the part sticking out of the acid), however there is hydrogen generated in the acid also. If the distance of the cathode to the anode (cavity) is insufficient, the hydrogen stream in the acid can reach the niobium surface and possibly can be dissolved in the material. This should not happen, if the set-up is optimized and the hydrogen is prevented from reaching the niobium surface, which is either inside the acid bath or outside (the top part). As reported in [10], the appropriate adjustment of the cathode distance and hydrogen screen is a very important parameter for successful electropolishing conditions.

It is recommended that a series of electropolishing tests (most efficiently with single cell cavities) with modified cathode and cathode screen distances is undertaken and the cavities are checked for Qdisease

Hopefully, the result of these tests will be an optimized electropolishing configuration, which does not lead to hydrogen pickup by the niobium surfaces.

C)." On-line" monitoring and control

It has been experienced that the material removal on a typical cavity surface is non-uniform. Even though the aluminum cathode is shielded at the irises and the major voltage drop supposedly happens close to the anode, there is nearly a factor of 2 difference in material removal between iris and equator of a cavity (the smaller amount is removed at the equator). Whether this difference is due to different polarization curves in the two cavity regions or due to temperature gradients or due to different acid flow patterns is not clear. It has , however, been established recently [12] that a shaped cathode leads to a more uniform polarization curve over the entire surface and should result in a more uniform material removal. Besides an experimental program, which can explore such improved conditions with cavity tests, DESY has recently acquired a computer simulation program from the University of Bruxelles, which can be used to simulate different polishing conditions and configurations as well as flow patterns.

During the electropolishing process the concentration of hydrofluoric acid, which is essential for good polishing conditions, is reduced and the polishing conditions are changing. For maintaining reproducible polishing conditions it seems to be important to implement in any EP system an "on-line " monitoring of HF concentration and of the polarization curve.

- <u>It is recommended to explore to its fullest the simulation program (</u> <u>this is happening already at DESY)</u>
- <u>It is recommended to implement in any existing EP system "on line"</u> <u>monitoring and data logging of polarization curves and HF</u> <u>concentrations</u>
- <u>It is recommended to investigate with an experimental program the</u> <u>causes for the non-uniform material removal by e.g. modifying the</u> <u>temperature distribution, the acid flow pattern, the cathode shape, the</u> <u>cathode shielding or the location and number of current leads.</u>

D). Acid Composition

It has been reported at the TTC meeting in Frascati that at least one delivery of pre-mixed acid (" Honeywell Mixture", 10 parts HF, 85 parts H_2SO_4) to DESY in summer of 2005 had an unusual composition [9] and behaved differently during the electropolishing. It has been "hypothesized", that exposure of the mixture to hot weather during the delivery caused the modifications.

DESY is pursuing the industrialization of the electropolishing process with the company Henkel, mainly with single cell cavity preparations so far. Henkel is mixing the EP solution "in house" with nominally the same ratio of acids as in the "Honeywell mixture", however, the company reports a much more "active" mixture.

• It is recommended that the subject of acid composition and different behaviour of nominally the same mixtures will be addressed; most likely, this can be done by chemical analysis and comparison of polarization curves measured on samples under identical conditions. The table below summarizes the proposed R&D activities:

Problem	Proposed Activity	Priority					
Contamination Field Emission	Rinsing studies with samples (XPS,SIMS) Rinsing studies with single cell cavities						
Non-reproducible	Test any electropolished cavity for Q-disease	1					
appearance of	Can overheating during initial rinsing cause Q-disease?	2					
Q-disease	Optimizing studies for cathode/screening geometry	2					
Monitoring and control	Implementation of "on line" monitoring and data logging of polarization curves and HF concentrations	1					
	Exploitation of EP simulation program	1					
	Investigation of the cause for non-uniform material						
	removal	2					
Acid composition/ decomposition	Chemical analysis of acid mixture (nominally equal) Polarization curves on samples	2					

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Summary of electropolishing discussions at Frascati TTC meeting on 5-7 December 2005 and at smtf meeting at fnal on 5-7 october 2005

Tsuyoshi Tajima* for the Working Group attendees

Abstract

*tajima@lnal.gov

This document presents an outcome of the discussions at the TTC meeting at Frascati on 5-7 December 2005, which was a continuation from the SMTF meeting held at FNAL on 5-7 October 2005. Our goal was to identify the cause of the results spread of EPed 9-cell cavities that have been tested mostly at DESY. While the spread might not have been caused only by the EP itself, the fact that the spread is larger than BCPed cavities may suggest that the EP process or EP-related contamination due to such as sulfur may be the cause of the problem. After the discussions on EP parameters and current issues, we suggest that the following be carried out with R&D efforts as highest priority items: 1) further study how important it is to control HF content and what is an appropriate range, 2) establish the best way to eliminate sulfur, a reaction product while EP and is insoluble to water, and 3) study effectiveness of pre-polishing such as CBP at KEK. In addition, we encourage other ongoing R&Ds including vertical EP studies as supporting elements and WG1 was led by P. future cost reduction. Kneisel, K. Saito and D. Reschke at the TTC meeting and all the presentations can be found at

http://www.lnf.infn.it/conference/ilc05/program

<u>me.html</u>. The SMTF meeting at FNAL was led by T. Tajima and C. Boffo and the presented files are shown at <u>http://ilc-</u> dms.fnal.gov/Workgroups/SMTF/Collaboration Meetings/SMTF Collaboration Meeting Oct 5,6,7 2005/.

ACRONYMS

ANL	Argonne National Laboratory									
BCP	Buffered Chemical Polishing									
CBP	Centrifugal Barrel Polishing									
CEA	Atomic Energy Comission, France.									
DESY	Deutsch Electron Synchrotorn									
	Laboratory									
EP	Electro-Polishing									
GMR	Giant Magneto Resistance 2 nd order									
	gradiometer									
HPR	High Pressure (water) Rinsing									
HRC-EP	Horizontally Rotated Continuous									
	Electro Polishing									
INFN	National Institute of Nuclear									
	Physics, Italy									
INFN/LNI	LINFN Legnaro									
INFN/Mi	INFN Milano									
KEK	High Energy Accelerator Research									
	Organization, Japan.									
QA	Quality Assurance									
SMTF	Superconducting Module Test									
	Facility									
TTC	TESLA Technology Collaboration									
WG	Working Group									

INTRODUCTION

The HRC-EP that was developed by KEK and Nomura Plating company [1] has been adopted by DESY and JLAB. DESY has carried out 90 EP processes since it started in 2004 for a total processing time of 199 hours [21]. JLAB has processed a few 700-MHz, 805-MHz and 1.5-GHz multi-cell cavities with their system and has identified some issues to improve their system, although due to funding shortage they have not been able to do a lot on EP in the recent years.

The major goal of this WG was to discuss EP parameters and the reason why the spread of EPed 9-cell cavities is so large, i.e., $20 < E_{acc}(MV/m) < 35$ as shown in Fig. 1 based on mostly DESY data [21]. We discussed important parameters, what are the issues that need further R&D and need to be clarified or solved.

There were some presentations on single/large grain cavities and seamless cavities, but they were excluded from this document to focus on EP.

BRIEF HISTORY OF EP

Peter Kneisel gave a comprehensive review of the history of EP that has been adopted for treating accelerator structures [3]. The following shows the brief history.

- In 1971, H. Diepers and coworkers of Siemens AG developed a new method of electropolishing Nb within a government funded collaboration agreement with the Kernforschungszentrum Karlsruhe (KfK).
- The process was subsequently used for the surface treatment of cavities (RF separator, helix, R&D) at KfK.
- In ~1975, it was "exported" to HEPL [5], Cornell and KEK.
- In ~1980, K. Saito and Nomura Plating company modified and developed the HRC-EP method for 508 MHz 5-cell TRISTAN cavities [1]. The EP related figures in Refs. [1] and [8] are shown in Appendix A.

Appendix B shows chemical reactions that can occur during EP.



Cavity performance since Jun 05

Figure 1: Performance of EPed DESY 9-cell cavities since June 2005 [21]. Red diamonds show the results after 120 °C baking and the purple squares show those after fast cool down of the cavities that have Q disease.

INSTITUTES THAT HAVE EP CAPABILITY

Table 1 shows a list of institutions and their experience. Presently, DESY and KEK/Nomura have the full capability of electropolishing 9-cell cavities. JLAB has a facility that is large enough to accommodate a 9-cell cavity, but they have no experience so far. Appendix C shows the EP facilities at DESY, JLAB and KEK/Nomura. Appendix D shows small facilities for shorter cavities or for sample tests.

Table 1: List of institutions that have EP capabilities.

Institution	Facility	Experience	Ref.
ANL	for low- β	Since late	[14]

Institution	Facility structures	Experience 1960s	Ref.
CERN	1-cell	Since 2001	??
Cornell	Vertical EP	Since 2003	[10]
DESY	Sample tests	Since 2001	
DESY	HRC-EP	Since 2003	[6,7]
FNAL	Small tests	Since 2004??	[13]
JLAB	HRC-EP	Since 2003??	[9]
INFN/LNL	R&D on GMR and Automated EP	Since 2004	[2]
KEK	HRC-EP	Since ~1980??	[1,8]
Saclay	Small tests & mono- cell	Since 2004??	[11,12]

IMPORTANT PARAMETERS

The parameters in Table 2 have been agreed to be important and most of them have been the same as or scaled from the data described in K. Saito's paper [1]. These ranges were mostly determined by sample roughness and brightness measurements.

Table 2: Important EP Parameters.

Parameter	Range	Notes					
Current density	$\frac{30-100}{\text{mA/cm}^2}$						
Voltage	8 – 16 V	depending on the current density and HF content					
Bath temperature	25 – 35 °C						
HF concentration	60 – 90 cc/L						

Rotational speed	<1.8 rpm??	scaled from 0.7 rpm for 508 MHz
Acid flow rate	?? l/min	scaled from 60 l/min for 508 MHz cavities

Another important fact is that the viscous layer on the anode (Nb) surface needs to be preserved for EP to occur, i.e., too much turbulence that breaks this layer will lead to an unsuccessful EP.

MATERIALS

Some materials have been found incompatible with the EP acid. They are:

- Viton: There are various types of Viton and there might be compatible Viton.
- PVDF: DESY has used this for the part that needs welding since this is the only material that seemed compatible and weldable.

Teflon® or polytetrafluoroethylene (PTFE) is the ideal material to be used wherever possible.

Other issues related to materials that need to be reminded are:

- The cathode needs to be made of a pure aluminum (1100) to avoid corrosion.
- The tubes for heat exchanger could be pure aluminum, but the EP acids need to be mixed elsewhere before adding to the heat exchanger to avoid corrosion of Al tubes. (ANL uses Al tubes.)

NEW RESULTS AND OTHER ISSUES

Recent studies with 9 cm^2 samples at Saclay supported by EU CARE program have shown the following results [12].

- After 5-7 g/L Nb has been reached, the surface state starts to degrade. This, however, seems to be at least partially due to a decrease of HF content and could be different for actual cavities.
- The increase in HF content increases polishing rate, Nb solubility and acid solution lifetime, and it decreases the production of sulfur. The drawbacks, however, are corrosion of Al cathode, safety issues and difficulty in temperature control due to high removal rate.

DESY has found the following issues.

- The acid mixture delivered from a company was not the right mixture in the past, suggesting that the QA of delivered acid is an important issue.
- Some EPed cavities show Q disease, but not all the cavities, which may suggest that there were some difference(s) during EP process, although they could not find any difference in recorded operating parameters.
- There seems to be difference in removal rates in different cells according to the field flatness measurements. KEK has not had this problem, although they have checked with only one 9-cell cavity so far. This could have been an effect of handling after the EP [22].

POSSIBLE CAUSES OF EPeD CAVITIES RESULTS SPREAD

The question whether it is due to EP itself or to the subsequent process remains to be answered. However, assuming that the subsequent process has been the same quality as BCP cavities, the following are the possible causes that have been discussed so far.

- The EP parameters have not always been controlled to be within the range shown in Table 2.
- Removal of chemical contaminations such as sulfur was not always complete.
- The quality of the delivered acid mixture was not always the same.
- The initial cavity surfaces before EP were not the same quality among different cavities.

R&D ITEMS

Table 3 shows the currently ongoing R&D efforts at various laboratories. Through the discussions at Frascati and FNAL, we have identified the areas where we need to intensify R&D in a timely manner. They are:

- Effect of controlling HF content and determine an appropriate range for proper EP.
- Effect of eliminating sulfur with either oxipolishing, H₂O₂ rinse or methanol rinse, etc.
- Effect of pre-polishing such as CBP on the results spread. Currently, KEK is the only place where an advanced CBP facility is available and hopefully they can do this R&D expeditiously.

Table 3: Ongoing R&D's on EP at various institutions.

Institution Topics

Cornell Vertical EP

DESY Parameter validataion with 1cell (with Henkel), components optimization with 9-cell cavities

FNAL	Papameter study with small samples					
INFN/LNL,	Automated EP					
INFM/Naples U. Naples [2]	Magnetometry for better cathode configuration					
JLAB	Parameter validation, Continuous monitor and addition of HF					
KEK/Nomura	Effect of CBP on the EP reproducibility					
Saclay	Parameter validation, solution aging, method of surface qualification					
U. Bruxelles	Analyses of EP phenomena??					
U. Wuppertal	Surface roughness measurement with Laser					

COORDINATION OF EP R&D

While there are regional programs such as CARE that include EP studies, establishing a more global coordination is desirable to conduct more focused R&D in a timely manner. The following are suggestions that might expedite the R&D.

- Initiate the global R&D effort soon.
- Open a web page specialized on EP R&D
- Make an e-mailing list and circulate eLetters as frequently as possible to disseminate new results for discussion.

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Figure A.1: Schematic representations of leveling effect by EP (left) and typical I/V curve during EP (right).



Figure A.2: Roughness and brightness as a function of voltage.



Figure A.3: Roughness and brightness as a function of current density.



Figure A.4: Roughness and brightness as a function of ratio of anode to cathode surfaces.



Figure A.5: Roughness and brightness as a function of bath temperature.



Figure A.6: Current density vs. voltage and various surface states resulting from these conditions.



Figure A.7: Typical surface roughness and photograph for each polishing reason.



Figure A.8: Sample test on a refreshing method of an EP solution by the addition of HSO_3F .



Figure A.9: Roughness and brightness as a function of the amount of dissolved Nb.



Figure A.10: Roughness and brightness as a function of HF concentration.



Figure A.11: HF content as a function of voltage to keep the current density at 50 mA/cm^2 .



Figure A.12: Effect of adding HSO₃F on the amount of dissolved Nb.



Figure A.13: Change of weight as an indication of absorption of EP solution for various materials.



Retention time(arbit. unit)

Figure A.14: Dissolving of plastic materials and Viton into an EP solution for two months soaking.



Figure A.15: Roughness as a function of the anode speed relative to the EP solution.



Figure A.16: Roughness and brightness as a function of cavity rotation speed. The cavity was a 1.5 GHz single cell.



Figure A.17: Roughness vs. flow rate at a rotation speed of 1 rpm. One 1.5 GHz single-cell cavity was used.



Figure A.18: Roughness as a function of EP solution temperature at a rotation 1 rpm and a flow rate of 1.3 l/min.



Figure A.19: Flow chart of the EP system for the TRISTAN 508 MHz 5-cell cavities.

APPENDIX B: CHEMICAL REACTIONS THAT OCCUR DURING EP

 $\begin{array}{l} 2Nb + 10HF + 2H_2O \Longrightarrow 2H_2NbOF_5 + 5H_2 \\ (B.2) \ [??] \\ Nb_2O_5 + 10HF \Longrightarrow 2H_2NbOF_5 + 3H_2O \\ (B.3) \ [15] \end{array}$

Cathode corrosion (Al) and Sulphur deposition

$$2Al + 4H_2SO_4 \rightarrow Al_2(SO_4)_3 + (S \downarrow) + 4H_2O$$

solution \rightarrow alcohol rinse (B.

4) [15]

APPENDIX C: 9-CELL CAVITY EP MACHINES IN THE WORLD



Figure C.1: DESY in Germany. [16]



Figure C.2: JLAB in the U.S.A. [18] ??

Figure C.3: KEK/Nomura in Japan. [17]

APPENDIX E: SINGLE-CELL AND SMALL EP MACHINES



Figure D.1: Henkel company in Germany. [16]



Figure D.2: CEA/Saclay in France. [2].

Chemical											
surface											
treatment											
process											
			12/5/05	·		KEK		FNAL			DESY
	1	units	Decision	DESY	Jlab	(Nomura)	KEK (STF)	SMTF	ANL	Cornell	Henkel
Electropolishing				EP 1/9	EP 1/5	EP	EP 1/9				
	Situation		·	Horiz	Horiz	Horiz	Horiz		filled	vertical	Horiz
		· · · · ·	,	const	<u>ر</u> ا	const					
	Control	·'	'	voltage	<u> </u>	current	continuous	'			
	「 <u>,,</u> ,,		· [·		<mark>⊿</mark> '	15.05	const	<u> </u>		T	(10, 10)
	Voltage	V	<u> </u> '	17?	└──── ′	<u>15-25</u>	current	 '	15 20		(12-18)
	1	'	'	[/				/ '			
	mode	'	'	continuous	continuous	continuous	15-25	/ '	pulsed		continuous
		mA /	+	Continuous	Continuous	Continuedo	10-20	 '	30 to		Continuous
	Current	cm^2	· · · · · · · · · · · · · · · · · · ·	49-58	1'	40~50	40-50	l _'	50		
		W /	,		1	· · · · · · · · · · · · · · · · · · ·					
	Power	cm^2	<u> </u>	1	↓' '	 '		 '	<u> </u>		ļ
	Temperature of liquid (start-			04.05	1		05.00	/ '	00.00		00.00
	end)	C C	'	24-35	+'	25~32	25-32	 '	28 32		22-30
	Temperature of cavity Acid flow rate	l/min	'	9-11	t'	30~35 6	<u>30-35</u> 6	 '	aritato		(7.5)
	rotation speed		'	9-11 1.5-2	1	6 1,4	6 1,4	 '	agitate		(7.5)
		rpm	·'	360	180	1,4	1,4	 '		+	(0.5)
	H2 screen details	'	,	degrees	degrees	degrees	degrees	Δ΄			none
	nitrogen purge for H2	·'	+	30lpm	1cfm	none	none	 '			
	cathode masking	('	· 	iris/BT	iris/BT	iris/BT	BT				<u> </u>
	seal material		++	PVDF	,	viton	viton			1	
	Tolerable Nb content	gpl	· · · · · ·	10	· · · · ·	9	9				
	,	<u> </u>	· · · · · ·		1 '	· · · · · · · · · · · · · · · · · · ·			3003		[
	1	'	'	PVDF	PVDF	1 '		4 '	series		
	Heat exchanger	 '	'	tube	tube	PFA tube	PFA tube	_ '	AL		
	Acid quality (grade)	<u> </u>	'	electronic	electronic	reagent	reagent	<u>'</u>	reagent		L

	storage volume		150	240	1000/100	1000			800
	masking material		PTFE tape	PTFE tape	PFA film	PFA film			
	cathode to NB ratio		•	•					
					1100	1100			
	Cathode material	AL purity	100		series	series			
	Cathode shape		tube	tube	tube	tube			shaped
	Cathode dia		1.0 inch	1.3inchs	25 mm	25,0			
		micron /							
	etching speed	min	0,4		0,4	0,4			
	total removal	micron	180-200		80	80	150		
	additional removal	micron	?		30	30			
	total time for a treatment	hr	6+2 h		3.5	3.5			
			2 stif ring,						
			2 dish		all EQ plus	all EQ plus			
	contact location		head		beam tube	beam tube			
	experience		> 200hr		> 3600 hr	0			
	diff temp in to out	С	8		10				
Care after EP									
	water rinsing	min	60	60	60 *	60			
	drying	min	0	30	0	0			
	Time till HPR	min	120	30	30~45	30~45			
					50C only	50C only			
					for 9cell	for 9cell			
	water temp of rinse	С	20	29	case	case			
	conductivity water out	uS	400		use UPW	use UPW			
		Mohm-							
	resistivity water out	cm							
Chemical									
polishing			BCP 1:1:2	BCP 1:1:2	BCP 1:1:1	NA			
ponsning		micron /	001 1.1.2	001 1.1.2	DOI 1.1.1				
	Etching speed	min	1,1-0,9	1.2-0.7	8~10 **				
			.,,.		Room				
	Acid Temperature	С	15-18	10	temp				
	Soak time	min			1~2				
	Acid Flow rate	l/m	3-20	15,2	stirring				
	Drain time	sec	80	,_	20 ***				
					pre-				
	Purpose				cleaning				

		1							1	1	1
										1	
										1	
	-	-	-	-	-	-	-	=	-		-

High										
Pressure										
Rinsing for										
Assembly										
Assertiony	4		12/5/2005					KEK AR-		
	I	units	Decision	tol	DESY	Jlab	KEK Nomura	east	KEK STF	FNAL (A0)
Basic parameters										
	Pressure after final filter	bar	70-120		100	96	8 0 ***	70	70	83
	Period	hr/cell	i	├ ─── ′		0,83	1	1	1	0,125
	Flow rate	liter / min	·	 	15-20	9,1	10	10	10	18
	rotation/up- down		separate motion				separate	separate	separate	
	Cavity Rotation		ı I			2	15	45		10
	speed Wand up	rpm	! 	<u> </u>	ļļ		15	15	15	10
	down/speed	cm/min	·'	<u> </u>	<mark>ا ــــــــــــــــــــــــــــــــــــ</mark>	1	22	22	22	3,5
Water quality			·′				· · · · · ·			12.0
	Resistivity TOC	MΩ cm	·'	<u> '</u>	18,2	18,2 < 6	18 ~15	6 ~150	18 10	18,2 <20
	Bacteria	ppb	'	├ ───′	<1	<u> </u>	~15	~150	10	<20
	count	cfu	!'	'	۱۱	< 50	<1	~10	< 1	<20/liter
	meas. Point		·	<u> </u>	ا <u> </u>	POU	POU	POU	POU	in line
	Particle count at pressure	counts/ml	 			0,88	Non	Non	Non	NA
	Nitrogen overflow		ا ا	<u> </u>	yes	cleanroom air	no	no	no	yes
Spray Head Nozzle										
	nozzle material		ا ا	ļ'	saphire	Ti	ss303	ss303	ss303	Sapphire
	head material		·'	 '	SS 1.4429	ss316L	ss303	ss303	ss303	SS316L
	number of holes		ا 	<u> </u>	8	2	8	8	8	8, 2 types
	hole size	Dia (mm)	۱ ــــــــــــــــــــــــــــــــــــ	<u> </u>	0,4	0,9	0,6	0,6	0,6	4-0.4,4-0.2

		angle in		+30 up -30					
	jet direction	degrees		down	40	-45, 0, +45	-45, 0, +45	-45, 0, +45	
	type of								
	nozzle			solid jet	fan jet	solid jet	solid jet	solid jet	
	errosion		<u>├</u> ───	no	?	Yes **	Yes **	Yes **	No
	measurement needed for all								
Filter									
	filter size	um		0,02	0,04	0,22	0,22	0,22	0,04
	location			POU	POU	POU	POU	POU	POU
	'								
Other cares									
	Cavity Environment			Class 100 (10)	Class 100 air brought in	Class 1000 air brought in	Class 1000 air brought in	Class 100 air brought in	Class 100 N
	dust free mechanism				?				N2 purge, roo vacuum
	potential difference between nozzle and cavity			under investigation	Unknown	10~20mV		10~20mV	
	grounded?			yes	no	No	No	No	
	particle migration free				?	In/Out isolation	In/Out isolation	In/Out isolation	
	Water Temperature	с		20	29	room temp	room temp	room temp	
Transportation									
	transfer from hpr to drying area	min		1	10	240	60	60	
	Transfer time from chem to HPR (EP)	min		45	60	90	90		
	Transfer time from chem to HPR (BCP)	min		3	30	60	30		3 hrs
	Transfer method (EP)			water filled	wet	wet	wet	wet	
	Transfer method			water filled	wet	water filled	water filled	water filled	Wet/filled

	(BCP)	1	1	1	1			1		4 '
	sealing after chem for transfer to									
	hpr	<u>ا</u> ــــــا	+'	 '	closed	closed	closed	closed	closed	/ '
Drying Process After										
HPR	4			f′	('	· · · · · · · · · · · · · · · · · · ·				
	when				after HPR	after HPR	after HPR or after assembly	after HPR or after assembly	after HPR or after assembly	after HPR
	method				Class 10 area	Class 10 area	evacuation	evacuation	evacuation	Hang under clas HEPA
	<u> </u>		'		'	<u> </u> '	<u> </u>	<u> </u>		'
Assembly				 '	<u> </u> '	 				
	Clean room class				10	10		10	10	10
Evacuation										
	Setup	 	'	↓′	+'	· '		for VT	for VT	
	++		· ['	t'	 '	·'	<u> </u> '	+		
	ļt	اا	ļ'	ب	, ,	ļ'		ļ		
Speciality					/					
		ا <u> </u>	· ۲	↓'	'	'	,'			
	Total time for the treatment	hrs	'	ļ'	ļ'	4	1 (Single) 6 (9-cell)	<	1 (Single) 6 (9-cell)	L
	Number of treatments needed for vertical test				1+6	2	1	1	1	
	Limitation on performance									
	<u> </u>	اا	'	'	'	'	'			<u>ــــــــــــــــــــــــــــــــــــ</u>

Image: Construction of the second		More investigation needed on		p	Too much HPR degrades performance?		
comments Image:							
Sometimes, drying is performed in clean room (class 10) with beam pipe open		Ranking??					
Sometimes, drying is performed in clean room (class 10) with beam pipe open							
drying is performed in clean room class 10) with beam pipe open		comments					
drying is performed in clean room class 10) with beam pipe open							
* during night. allways	*	drying is performed in clean room (class 10) with beam	allways				

Pure													
Water													
Facility													
							KEK						
							AR-	KEK					
			12/5/05		DESY		east	AR-east	KEK	KEK	FNAL		
_		units	Decision	DESY	1cell	Jlab	PW	UPW	(Nomura)	(STF)	SMTF	ANL	Cornell
Pure water													
	City water					_							
	prefilter size	um		none	10	5	None		Non	None			
	Carbon filter volume	m2				0.47	0,002		Non	0,05			
	Reverse	m3 single				0,17	0,002		INOLI	0,05			
	Osmosis	/dual											
	type	stages		single	single	single	single		Non	None	single		
	Permeate												
	rate	lpm		12	7	22,7	20						
	Concentrate												
	rate	lpm		6	3	9,1							
	Filter size	micron					0,1			0,1			
	Storage						1000						
	volume	liters		4000	500	3785,4	1300			450	3800		
									2				
								Use					
								KEK AR-					
								east PW					
Ultra-pure water	Circulation												
	Circulation rate	lpm		20		127,3		-		10	19		
	Loop	M-ohm-		20		121,3		-		10	19		
	Resistivity	cm		18,2	18	18,2		18	18	18	18,2		
	Water			· -, -		,_					· - ,		
	Temperature	С		15,2	20	29		RT	RT	RT			
	Number of												
	loops	#		2	1	2		2	1	3	1	ļ	
	Number of	<i>,.</i>		_					_		_		
	drops	#		5	4	8		3	5 UF	4	7		
	ultrafiltration size	um		0,02	none	0,02		0,1	UF module	0,1	0,05		
	5120	un	1	0,02	none	0,02		0,1	module	0,1	0,05	I	

	# post filters		1	1	2	1		1	2	
	post filter	um	0.2	0.2	0,54	0,1		0,1	0,2	
	UV				(194,					
	frequencies		?	?	256)	-	UV	UV	1	
	lon bed									
	workers	m3		46L	0,17					
	lon bed			101	0.47					
	polishers	m3		46L	0,17					
	loop	Atm	2	Obor	17			3	2.4	
	pressure Production	Aun	3	3bar	1,7			3	2,1	
	capacity	lpm	20			1	> 10	10		
		трш	20	0.5		30/cc	> 10	10		
	particle			0.5				None		
	count			(0.2um)		(0.15µm)		None		
POU Chemistry	700		0.4.4.4	7.40				10	N1.0	
	TOC	ppb	0,4-1,4	7-10	NA		~20	~10	NA	
	Bacteria	ofu	. 5		-50		50	5	. 50	
	count max	cfu	<=5		<50		50	5	>50	
	Bacteria count typical	cfu	<= 3		<50		<1	< 3	>50	
	Final Filter	Ciù	<= 3		<50		<1	< 3	>00	
	size	um	0,2		NA		Non	0,22	NA	
	Liquid	un	0,2		1.0.1		Hom	0,22		
	particle									
	count avg	counts/ml	0,08		0,09		NA	NA	NA	
	0									
POU HPR										
	TOC	ppb	<=1.41		<6		~20	10	<20	
	Bacteria									
	count max	cfu	0		>500		50/cc	5	100/liter	
	Bacteria									
	count typical	cfu	0		<50		<1/ml	< 3	10/liter	
	Final Filter									
	size	um	0,04	00:04	0,04		0,2	0,22	0,04	
	Liquid									
	particle									
	count avg	counts/ml	0,02		0,88		NI A	NA	NA	
	(0.3)	counts/mi	0,02		0,00		NA	NA	INA	
POU Part										
cleaning										
Cicaling						100 ~				
	тос	ppb	<=1,46		NA	300~		~10	NA	

Bacteria count max	cfu	0	NA	500	5	NA	
Bacteria count typical	cfu	0	NA	40/ml	< 3	NA	
Final Filter size		0,02	NA	0,1	0,22	NA	
Liquid particle count avg	counts/ml	1,04	NA	NA	NA	NA	

Heat treatment										
			12/5/05					FNAL		
		units	Decision	tol	DESY	Jlab	KEK New	SMTF	ANL	Cornell
Niobium Purification										
	Baseline									
	Pressure									
	(Room Temp)	mbar				<4e-7		NA		
	Ramp Rate	C/min				5		NA		
	Soak									
	Temperature	С			1350	1250		NA		
	Pressure at									
	Temp	mbar				4,00E-06		NA		
	Soak Time	min				180		NA		
	Ramp Down									
	Rate	C/min				NA		NA		
	Pump Capacity	l/s (air)				3000		NA		
	Duran Consolitie	l/s				5000		NIA		
	Pump Capacity	(hydrogen)				5000		NA		
	Chamber Hot					400				
	Zone size	cm-length				160		NA		
		cm-width				58		NA		
		cm-height				58		NA		
		processes								
	Experience	completed				40		NA		
				-						
High Temperature										
Baking/Annealing									5,00E-	
	Pressure Empty	mbar			<1e-8	<4e-7	1e-6 Torr	1,00E-07	08 08	
	Ramp Rate	C/min				5	20	<5	1,7	
	Soak	0,1111	600 ~			, , , , , , , , , , , , , , , , , , ,	20		1,7	
	Temperature	С	800~		800	600	750	750	600	
	Pressure at	0	000			000	100	100	5,00E-	
	Temp	mbar	1,00E-06			5,30E-05	6e-4 Pa	<8.0E-08	5,00⊑- 04	
		mour	1,002 00						<u> </u>	
	Soak Time	hrs	3			10	3	3	10	
	Ramp Down					10		5	10	
	Rate	C/min			NA	NA	~8 hy *	<1	~3	
	Pump Capacity	l/s (air)				3000	10000	500		
1		l/s								
-------------------------------	------------------------	------------------------	-------	-------------	------------------	-----------------	--------------------------------	-----	-----------------	--
	Pump Capacity	(hydrogen)				5000		750		
	Chamber Hot Zone	cm-length				160	300	76	140	
		cm-width				58	φ 5 0	16	75	
		cm-height				58		16	75	
	Experience	processes completed				200	10	6	2	
	temp before opening	С	50				100			
	surroundings				Bare??	Bare??	Ti box			
Low Temperature (120C) Baking										
	Purpose				Q improvement		oxydized layer treatment	NA		
	Temperature	С	120	(0,+15)	120-135	120	120	NA	120	
	Period	hr	10-48		48	48	48	NA	48	
	inside cavity				vacuum	vacuum	vacuum		vacuum	
	outside cavity				Nitogen	Atm nitrogen	air	NA	helium	
	Pump				oil free TMP		IP / TMP	NA	TMP (maglev)	

Evenuetion eveters									
Evacuation system									
for various stages									
<u>_</u>			12/5/05			KEK AR-		FNAL	
		units	Decision	DESY	Jlab	east	KEK STF	SMTF	ANL
UHV Systems for Cavity Evacuation									
									TMP
	UHV pump type			TMP	TMP	IP	TMP	TMP	(maglev)
	Pumping Speed (Air)	lps			60	250 TMP +	250	100	300
	Roughing pump type			oil free	scroll	Rotary *	Scroll	Rotary Vane	scroll
	Roughing pump speed (Air)	lpm			250	250	100	100	600
		ipin			1,00E-	200	100		000
	Typical Baseline Pressure	mbar			08	3,00E-08	1,0E-07	1,00E-08	1,00E-08
									He leak
	RGA	AMU			100	He detector	He detector	up to 100	check
UHV Systems for Vertical Test				oil free			NA		
	UHV pump type			TMP	TMP	No pumping		TMP	
	Pumping Speed (Air)	lps			60	-		100	
	Roughing pump type				scroll	-		Rotary vane	
	Roughing pump speed (Air)	lpm			250	-		100	
		•			1,00E-				
	Typical Baseline Pressure	mbar			08	-		5,00E-09	
	RGA	AMU			100	-		up to 100	
					Metal valve				
					or				
	Evacuation method during				active	Closed with			
	test				pump	metal valve		IP	
	Leak check after VT					He detector			
UHV Systems for Horizontal									
Assembly					TMP				
					and				
				oil free	ion		(IP + TMP)		TMP
	UHV pump type			TMP	pump		` X 2 ´	NA	(maglev
					00///		(250 / 250) x		
	Pumping Speed (Air)	lps			60/11		2	NA	300

Roughing pump type			scroll	Scroll X 2	NA	scroll
Roughing pump speed (Air)	lpm		250	100 x 2	NA	600
			1,00E-			
Typical Baseline Pressure	mbar		08	1,0E-07	NA	1,00E-08
						He leak
RGA	AMU		100	He	NA	check
as of assembly					NA	

	Cleanroom											
	for various											
	activities											
		units	12/5/05 Decision	DESY	Jlab	KEK AR-east	KEK Nomura	KEK STF	FNAL SMTF	ANL	Cornell	
Cleanroom areas												
	Chemical area											
	Sub component chemistry area	m2		101.6	20,9	-		0,5	10	18		
	Cleanroom class	FED 209E		10 000	NR			1000	NR	NR		Fed 209E
	Subcomponent degreasing area	m2		2.0	62,8	-			8	20		10
	Cleanroom class	FED 209E		10 000	NR				1.000	1000		100
	Cavity chemistry (BCP) area	m2		0.8	22,6				17	18		1000
	Cleanroom class	FED 209E		10 000	100				NR	NR		100.000
	Cavity Chemistry (EP) area	m2		35.4	36,5		30	120	17	18		
	Cleanroom class	FED 209E		outside cleanroom	10.000		Non	NR	NR	NR		NR-not rated
	Cavity HPR area	m2		1,5	22,6	9	12	3	9	23		
	Cleanroom class	FED 209E		10	100	1000	1000	100	100	100		
	Cavity assembly area for vertical test	m2		23	6,4	10		14	18	15		
	Cleanroom class	FED 209E		10	10	10		10	10	100		

	String assembly			400.7	45.4			07		
	area	m2		103,7	45,1		14	67	20	
		FED		40 / 400	100		 ISO		100	
	Cleanroom class	209E		10 / 100	100		4	10	100	
	Vertical stand area	m2			88,8	12	NA	10	?	
		FED								
	Cleanroom class	209E			100.000	NR		NR		
	Module assembly								linac	
	area	m2			117,8			100	tunnel	
		FED			, -					
	Cleanroom class	209E		none	NR		NR	NR	NR	
	Module staging								linac	
	area	m2			120,8			110	tunnel	
		FED			.20,0					
	Cleanroom class	209E			NR		NR	NR	NR	
		2002								
L340xc										
L340XC										

Component								
Component								
Cleaning								
Requirements								
Requirements								
		12/5/05	DEOV	11 - L	KEK AR-	KEK AR-		A N 11
Covity Ovelification		Decision	DESY	Jlab	east	east	KEK STF	ANL
Cavity Qualification								
	Input coupler, field probe assemblies		Untrasonic + UPW rinse	Ultrasonic + UPW rinse+ nitrogen dry	CP + Ultrasonic in PW	CP + HPR(PW) + Ultrasonic in UPW	CP + HPR(PW) + Ultrasonic in UPW	Ultrasonic+manual HPR
	UHV components		ultrsaonic +UPW + annealing	Ultrasonic + UPW rinse+ nitrogen dry		Ultrasonic in UPW	Ultrasonic in UPW	same
	Nut/Bolt Hardware		dish washer + Ultrasonic +UOW	Ultrasonic + UPW rinse+ nitrogen dry		Non	None	same
String Assembly								
	input coupler, pickup		UPW Ultrasonic baking	Ultrasonic + UPW rinse+ nitrogen dry	CP + Ultrasonic in PW			Ultrasonic+manual HPR
	UHV components		ultrsaonic +UPW + annealing	Ultrasonic + UPW rinse+ nitrogen dry				same

	Nut/Bolt Hardware	dish washer + Ultrasonic +UOW	Ultrasonic + UPW rinse+ nitrogen dry		same
Horizontal Test (Chechia)					
	UHV components				
	Nut/Bolt Hardware				
Module Fabrication					
	UHV components		Ultrasonic + UPW rinse+ nitrogen dry		
	Nut/Bolt Hardware		Ultrasonic + UPW rinse+ nitrogen dry		





TTC-Meeting at KEK 2006 Sept.25-28, 2006

Analysis technique of the HF-H2SO4-electrolyte

Christian Hartmann Henkel Lohnpoliertechnik GmbH





Location	Austria Waidhofen/Thaya	Germany Neustadt-Glewe	Hungary Györ
Foundation	1977	1996	1994
Employees	40	40	7
Business Activities	Stainless steel technology, pickling, passivation, electropolishing, clean room techniques	Stainless steel technology, pickling, passivation, electropolishing, clean room techniques	Stainless steel technology, pickling, passivation, electropolishing
Production Area	approx. 6.500 m2	approx. 4.500 m2	approx. 2.000 m2
Clean Rooms	Clean rooms 100.000, 10.000, 100 and 10 (US-Federal Standard 209 D)	Clean rooms 100.000, 10.000, 100 and 10 (US-Federal Standard 209 D)	
Electropolishing Baths	up to 80.000 ltr.	up to 23.000 ltr	up to 9.000 ltr.
Pickling Baths	up to 60.000 ltr.	up to 23.000 ltr	up to 9.000 ltr.
Electropolishing Machines	for internal ep of tubes with diameters 1 350 mm and lengths up to 18.000 mm	for internal ep of tubes with diameters 1 350 mm and lengths up to 18.000 mm	
Auxiliary Supplies	Deionic ultra pure water installation (18MWcm at 25°C, TOC < 50 ppb, KBE< 10/100 ml, particle filter 0,1 µm), cryo source for ultra pure nitrogen (quality N2 5.0, particle filter 0,003µm)	Deionic ultra pure water installation (18MWcm at 25°C, TOC < 50 ppb, KBE< 10/100 ml, particle filter 0,1 µm), cryo source for ultra pure nitrogen (quality N2 5.0, particle filter 0,003µm)	Reverse Osmose Installation (4MWcm at 25°C)





Analysis technique

- Titration
- **ICP-OES** (inductively coupled plasma- optical emission spectroscopy)
- **IC** (ionic-chromatography)
- **TOC** (total organic carbon)
- **NMR** (nuclear magnetic resonance)
- **FTIR-ATR-probe** (Fourier transformation infrared spectroscopy –attenuated total reflection)





Production process of Henkel electrolyte

• Warm test

- mixing HF-acid (75%) with *normal* water
- => HF acid (46%)
- mixing HF-acid (46%) with H2SO4 (98%) *without cooling* in the rate of 1/9
- the reaction ist hot more than 60°C and steaming
- Rust impurities are possible

Cold test

- mixing HF-acid (75%) with *deionised* water
- => HF acid (46%)
- mixing HF-acid (46%) with H2SO4 (98%) <u>cooling</u> <u>under 20°C</u> in the rate of 1/9
- less steam and storing always under 20°C





Titration (volumeric analysis)

Total Acidity per titration (measured by Solvay-Lab):

Warm testCold test84,8 % (84,64 - 85,1)84,4% (84,0 - 84.6)H2SO4

Total acid as H2SO4, fluoride bounded to calcium - 6 titrations

- + automated definition of total ionic concentration possible
- you must know what you want to analyse (selection of titration solvent)

Costs: approx. 10.000 - 15.000,- € Producer: Metrohm, Schott, Mettler-Toledo





ICP-OES (optical emission spectroscopy)

Principle: the testsubstance is ionised in an argon plasma (6000K– 12000K), the effect is an optical emission you can analyse in a spectrometer

- + simultaneous multielement analyse upto 70 elements (qualitative und quantitative)
 better repeatability than AAS because insensitivity of interferences
- no information about molecular characteristics

costs: approx. 60.000,-€ producer: PerkinElmer, Varian, Spectro, Thermo...





	ICP	-OES	(optical emi	ission :	spectroscopy)
-	lvay (T in mg/k		ICAP 6500)		
	warm	cold		warm	cold
Nb	<0,1	<0,1	Zn	<0,1	<0,1
Та	<0,1	<0,1	Pb	<0,1	<0,1
Na	1,4	1,4	Cd	<0,01	<0,01
Κ	1,1	1,5	V	<0,1	<0,1
Mg	0,4	0,2	Мо	<0,1	<0,1
Ca	0,9	1,2	W	<0,1	<0,1
Sr	<0,1	<0,1	Sn	<0,1	<0,1
Ba	<0,1	<0,1			
Ti	<0,1	0,3			
Zr	<0,1	<0,1			
Fe	32	14			
Cr	0,15	0,19			
Ni	0,14	0,14			
Mn	0,19	0,15			
Cu	<0,1	<0,1			





ICP-OES (Varian with Varian 735-ES)

Fe 238.204	K 766.491	Mg 285.213	Mn 257.610	Mo 202.032	Na 588.995
ppm	ppm	ppm	ppm	ppm	ppm
46.02	0.3915	0.4947	0.2493	0.0515	1.243
49.41	0.3790	0.5541	0.2720	0.0563	1.397
22.38	0.3845	0.2267	0.1375	0.0244	1.138
21.21	0.2513	0.2541	0.1353	0.0389	1.232
18.94	0.3104	0.2163	0.1269	0.0171	1.127
19.12	0.4483	0.2231	0.1309	0.0141	1.129
18.40	0.5197	0.2179	0.1256	0.0214	1.123
	ppm 46.02 49.41 22.38 21.21 18.94 19.12	ppm ppm 46.02 0.3915 49.41 0.3790 22.38 0.3845 21.21 0.2513 18.94 0.3104 19.12 0.4483	ppmppm46.020.39150.494749.410.37900.554122.380.38450.226721.210.25130.254118.940.31040.216319.120.44830.2231	ppmppmppm46.020.39150.49470.249349.410.37900.55410.272022.380.38450.22670.137521.210.25130.25410.135318.940.31040.21630.126919.120.44830.22310.1309	ppmppmppmppmppm46.020.39150.49470.24930.051549.410.37900.55410.27200.056322.380.38450.22670.13750.024421.210.25130.25410.13530.038918.940.31040.21630.12690.017119.120.44830.22310.13090.0141





IC- Ionic chromatography

- **Principle:** analysis technique for ionic species (anions and cations). Based on the characteristic of ions bounded to polar fixed adsorbent materials (ion exchange resin). The ions are different strong bounded, kind and size is critical for the species. Stronger bounded ions appear later in the chromatogram. The ion detection is mostly the result from the conductivity measurement.
 - + Simultaneous multi anions analysis + concentration definition
 Good reproducible
 More from SACLAY: F-, sulfat, SO₃F-
 - Only ion detection no information about molecules
 Only diluted solutions

Costs: >15.000,-€ Producer: Thermo, Dionex, Shimadzu, Metrohm...





IC- Ionic chromatography

Solvay Lab: Dionex IC500

warm cold 0,73% 0,77% F-2,76% 3,05% FSO3H

total fluoride is incapabel of measurement by IC – no total hydrolysis of FSO3H in H2SO4 and HF







IC- Ionic chromatography

Solvay Lab:

Measurement of total fluorid is possible by destillation

=> complete disintegration

Metrohm Ionicmeter Typ 692 (fluorid. standard + TISAB)

Result:	Warm	Cold
	2,62%	2,99% total F-
=>	2,75%	3,14% HF

Infraserv Knappsack Lab:

Warm1		Cold5
82%	81%	H2SO4
1,0%	1,1%	F-
3,9%	4,0%	FSO3H





TOC (total organic carbon)

Question: Are there any organic impurities in the electrolyte?

Solvay Lab TOC-Laboratory Analyser: Shimadzu Calibration: 5mg/I C

Result:WarmCold30 mg/kg59 mg/kg

the result is near the limit of quantitation!!





NMR (nuclear magnetic resonance)

Principle: Atoms with magnetic dipole arrange themselves in an external magnetic field (parallel or anti-parallel). These conditions differ by a certain amount of energy. The transition can be enforced by irridation of electromagnetic radiation at a specific frequeny: Lamorfrequency. The necessary frequency for the transition is measured. The result delivers conclusion about the electronic surrounding of the examined atomic nucleus and thus about the structure of the molecule.

- + Molecular structures are precisely determinable Interaction between molecules can be analysed
- Analysed atomic grade requires magnetic dipol moment (at 1H, 19F) Gases are not analysable
- Costs: >>100.000,-€ to some extent up to 4Mill. €; external: each measurement 170,-€ - 600,-€ according to measuring time Producer: Brukeroptics, Varian,...







HENKEL Lohnpoliertechnik GmbH An der Autobahn 12 / D - 19306 Neustadt-Glewe (M-V) Tel. +49 (0) 38757 66 0 / Fax. +49 (0) 38757 66 122 / Email : info@henkel-epol.com / www.henkel-epol.com





NMR Infraserv Cold (1H-NMR)



HENKEL Lohnpoliertechnik GmbH An der Autobahn 12 / D - 19306 Neustadt-Glewe (M-V) Tel. +49 (0) 38757 66 0 / Fax. +49 (0) 38757 66 122 / Email : info@henkel-epol.com / www.henkel-epol.com





(FT)IR (Fourier transformation infrared) Spectroscopy

Principle: Wave lenghts dependent stimulation of bonds between atoms for mechanical oscillation through absorption of light within the IR-range (wave lenghts of approx. 0,8-500 µm). The hereby obtained interferogrammes contain the complete radiation absorption of the trial after wave length and intensity as Fourier sum of all spectral lines. Resultant is a better dissolving ability as with the classic IR-spectroscopy.

- + Direct measurement of properties of the electrolyte Qualitative and quantitative analyses are possible
- Main problem : electrolyte resistant glas materials for cuvettes must be found (and all the same transparent in the IR-range)

Costs: >15.000,-€ Producer: Varian, Brukeroptics, Shimadzu, Thermo,...





ATR-Probe (attenuated total reflection)

Principle: Total reflectance at the interfaces is used. At total reflectance the radiation intrudes a little into the surrounding medium. Depending on whether or not the trial absorbes radiation the intensity of the reflected radiancy is therewith influenced. The result is a transmission spectrum similar to the reflection spectrum.

- + Direct measurement of properties of the electrolyte Diamond resistant against aggressive media, Mobil
- Contact between electrolyte and diamond mounting must be prevented (Teflonseals ?)

Costs: only ATR-unit : 10.000-15.000,-€ Provider: HiTec Zang, C3





ATR-Probe (attenuated total reflection)

HiTec Zang ATR-Probe used by RWTH Aachen











ATR-Probe (RWTH Aachen with HiTec Zang)







Summary

- Titration
- ICP-OES
- IC + destillation
- **TOC**
- NMR

- + total acidity
- + all elements (Nb, Fe,...)
- + Ions (SO4, F-, FSO3H)
- + organic impurities
- + organic impurities 222
- FTIR-ATR-probe ???

To Do: analyse more tests!!! (with impurities and Nb) Compare the tests with the results of the cavities